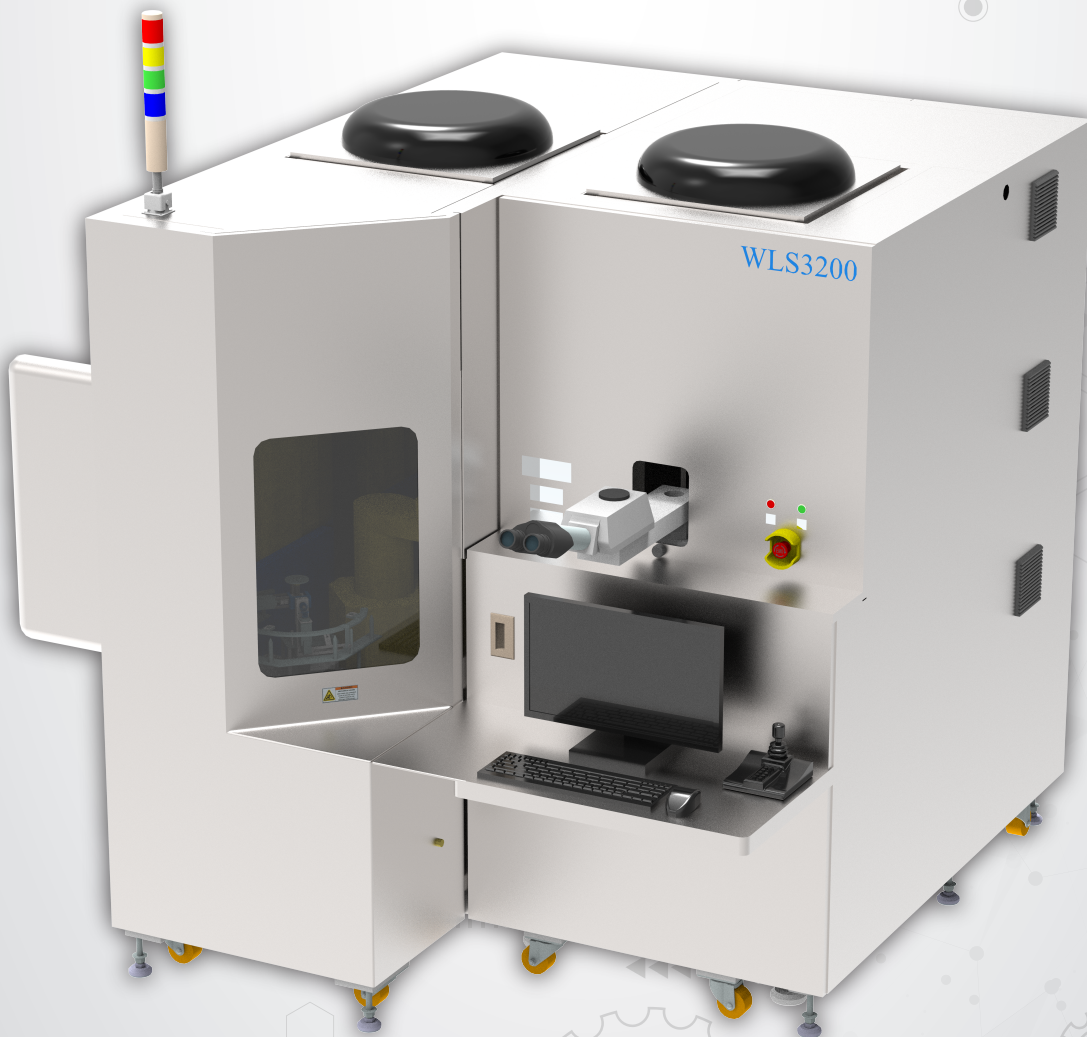


Automatic Wafer Loader & Microscope Inspection System



The WLS3200, a fully automated system for macro / micro inspection and overlay measurement

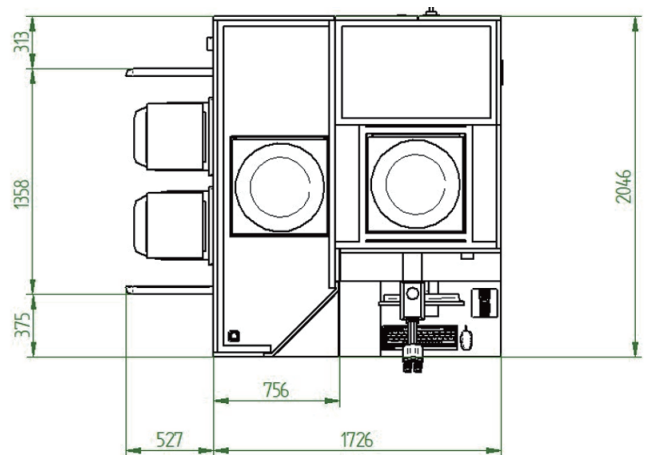
Easy Operation

- Maintain complete control of the entire system using the intuitive controller software.
- Integrated workflow for fast top and back macro inspection
- Improve productivity with the fully motorized microscope unit armed
- with active auto-focus and automatic brightness controls.

High Reliability

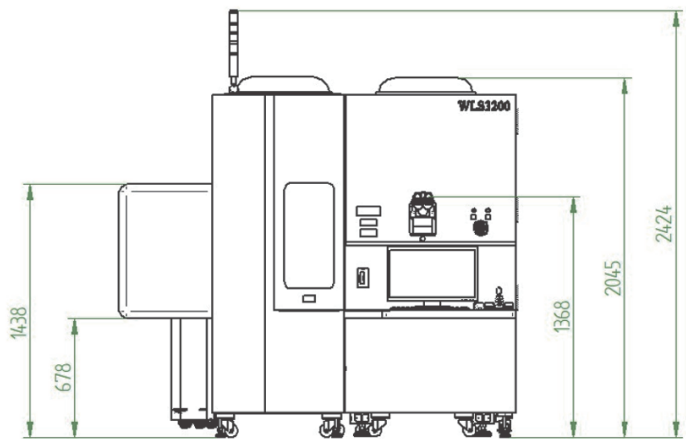
- Provide secure wafer transfer and precision imaging results with pre-aligner, auto-image alignment, and vibration isolation.
- Minimize contamination and handling errors with the fully enclosed and positive air pressure mini environment.

Dimensions



Specifications

Wafer Size	300mm / 200mm
Types of cassettes	FOUP/FOSB/SEMI
Number of cassette	2
Wafer handling	Rotary transport robot arm
Inspection mode	Top macro, back macro, 2nd back macro micro inspection
Observation mode	BF, DF, DIC(optional), IR(optional)
Vibration Isolation	Air suspension type
Utility	AC220V – 240V 7.0kVA 50/60Hz Vacuum -67kPa – -80kPa 20L/min Air 0.5Mpa to 0.6Mpa 160L/min
Stage	Motorized vacuumed XY and 360° rotation
Weight	1450kg



元利儀器
YUAN LI INSTRUMENT CO., LTD.

50 YEARS
SINCE 1970

114 台北市內湖區陽光街365巷39號6樓
6F, No. 39, Ln. 365, Yangguang St., Neihu Dist., Taipei City 114, Taiwan
+886 2 8751-2222

406 台中市北屯區文心路三段447號23樓之1
23F-1, No. 447, Sec. 3, Wenxin Rd., Beitun Dist., Taichung City 406, Taiwan
+886 4 2293-3161

802 高雄市苓雅區中正一路120號14樓之2
14F-2, No. 120, Zhongzheng 1st Rd., Lingya Dist., Kaohsiung City 802, Taiwan
+886 7 716-1295